



APPLICATION DATA SHEET

Electronic Version 14.0

Stylesheet Version v14.0

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|---------------------------------|---|---------|
| Title of Invention | ELECTRON DIFFRACTION SYSTEM FOR USE IN PRODUCTION ENVIRONMENT AND FOR HIGH PRESSURE DEPOSITION TECHNIQUES | |
| Application Type: | regular, utility | |
| Attorney Docket Number: | B1180/20019 | |
| Correspondence address: | | |
| Customer Number: | 03000 | *03000* |
| Priority Data: | | |
| Doc.No: | 02020889.8; Country - EP; Date: 2002-09-18 us-priority-claimed | |
| Inventor Information: | | |
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Assignee 1:

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